IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Yasunobu TAGUSA

Application No.: Currently unknown

Filing or 371(c) Date: Concurrently herewith

Title: METHOD FOR FABRICATING A SEMICONDUCTOR DEVICE AND APPARATUS FOR INSPECTING A

SEMICONDUCTOR

International Application No.: PCT/JP2005/004036

International Filing Date:

March 2, 2005

PRELIMINARY AMENDMENT

Mail Stop PCT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Prior to examination on the merits of the above-identified patent application,

Applicant respectfully requests entry and consideration of the following Amendment:

- Amendments to the Specification begin on page 2 of this paper.
- Amendments to the Drawings begin on page 5 of this paper and include an attached replacement sheet.
- Amendments to the Claims are reflected in the listing of the claims which begins on page 6 of this paper.
- Remarks/Arguments begin on page 11 of this paper.

Please note, if a box is not checked, then no corresponding amendment is being made.